

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/796,060	ISHIKAWA ET AL.	
Examiner	Art Unit	
Long Nguyen	2816	

SEARCHED					
Class	Subclass	Date	Examiner		
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INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
	DATE	EXMR		
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